

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: § Group Art Unit: TBD

Birgie Kuo §
8 Examiner: TBD

Serial No.: 10/625,432 §

Filed: July 23, 2004 §

For: MECHANISM FOR INTER-FAB §

MASK PROCESS §
MANAGEMENT §

INFORMATION DISCLOSURE STATEMENT

Commissioner For Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In compliance with the duty of disclosure under 37 CFR §1.56, and in accordance with the practice under 37 CFR §1.97 and §1.98, the Examiner's attention is directed to the documents listed on the enclosed modified Form PTO-1449. No inference should be made that the cited references are in fact material, are in fact prior art, or that no better art exists. The cited patents are listed in numerical order and are not in any order based on their pertinence.

The above-identified application was filed after June 30, 2003. Therefore, pursuant to the waiver of the requirement under 37 CFR 1.98 (a)(2)(i) as stated in a Pre-OG Notice dated July 11, 2003, a copy of only the non-patent literature listed on the enclosed modified Form PTO-1449 is attached.

This Information Disclosure Statement is being filed within three months of the United States filing date or before the mailing date of a first Office Action on the merits. No certification or fee is required (37 CFR §1.97(b)).

Applicant believes no fee is due. However, the Commissioner is hereby authorized to charge any additional fees which may be required or credit any overpayment to Deposit Account 08-1394.

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Respectfully submitted,

David M. O'Dell

Registration No. 42,044

Date: 1-21-04

HAYNES AND BOONE, LLP 901 Main Street, Suite 3100 Dallas, Texas 75202-3789 Telephone: 972-739-8635

Facsimile: 214-200-0853

File: 24061.100

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to Commissioner For Patents, P.O. Box 1450,

Alexandria, VA 22313-1450 on 1-22-04

Bonnie Boyle

Printed Name

Signature

In place of PTO-1449 Form

SHEET

U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

OF

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

| Complete if Known | | | | |
|------------------------|---------------|-----------------|--|--|
| Application Number 🔺 | 10/625,432 | 101.61 | | |
| Filing Date | July 23, 2004 | () | | |
| Applicant(s) | Birgie Kuo | JAN 2 9 2004 65 | | |
| 'Art Unit: A | TBD | 3 | | |
| Examiner Name | TBD | The second | | |
| Attorney Docket Number | 24061.100 | MARCHINA | | |

| U. S. PATENT DOCUMENTS | | | | |
|------------------------|---------|------------------------------|------------------|---|
| Examiner's | " Cite" | Document Number 6,537,844 | Publication Date | Name of Patentee or Applicant of Cited Document |
| | AA | 6,537,844 | 03-25-2003 | Itoh |
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| FOREIGN PATENT DOCUMENTS | | | | | |
|--------------------------|-------------|---|------------------|---|-------------|
| Examiner's Initials | Cite No. | Foreign Patent: Document (Country Code - Number - Kind) | Publication Date | Patentee or Applicant of Cited Document | Translation |
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| | OTHER PRIOR ART | | | |
|------------|-----------------|---|--|--|
| Examiner's | | | | |
| | AB | Kuo, Birgie, "Enterprise Mask Process Management", MIT e-Operations Symposium, Taiwan Semiconductor Manufacturing Co., Ltd. Manufacturing Information Technology Division (TSMC MITD), June 2003, 10 pages. | | |
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| Examiner | Date | |
|-----------|------------|--|
| Signature | Considered | |

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.